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Freestanding perovskite and infinite-layer nickelate membranes

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Abstract

Following the discovery of superconductivity in hole-doped NdNiO₂ infinite-layer thin films, extensive research has been conducted particularly to compare these materials with cuprates. Superconductivity has also been observed in nickelate thin films with other rare-earth elements such as Pr and La, but not in their bulk forms, suggesting a critical role for substrate-induced strain/interface or dimensionality effects. In this study, we used water-soluble (Ca,Sr)₃Al₂O₆ sacrificial layers to fabricate freestanding perovskite nickelate membranes and explore the phase transformation to infinite-layers of the membranes via topotactic reduction in the absence of any template effect from the substrate. Highly metallic NdNiO₃ membranes with bulk-like hysteretic metal-to-insulator transitions could be obtained when transferred from a LaAlO₃ substrate. The topotactic reduction of these membranes with CaH₂ was shown to be successful as characterized by the expected decrease of the out-of-plane cell parameter and absence of apical oxygens. The reduced membranes however displayed insulating characteristics similar to those of bulk infinite-layer nickelates. Our findings strongly indicate that a template is necessary to stabilize a coherent and robust infinite-layer phase with optimal transport properties.

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1 I. INTRODUCTION

2 Perovskite rare-earth nickelate heterostructures, $R\text{NiO}_3$ (R being a rare-earth), have been
3 the subject of intense theoretical and experimental research efforts. In particular a theoret-
4 ical proposal assumed that those materials could mimic the high-Tc superconductivity of
5 cuprates[1], for which a Cu-3d e_g orbital selective Cooper pairing is believed to be respon-
6 sible for the zero-resistance state[2]. Recently, soft-chemistry processes using CaH $_2$ powder
7 as a reducing agent have allowed the stabilization of a superconducting infinite-layer (IL)
8 phase in hole-doped $R\text{NiO}_2$ thin films (with $R = \text{Nd, Pr, and La}$) grown onto SrTiO $_3$ (STO)
9 substrates[3–5]. The absence of bulk superconductivity, even under pressure[6], highlights
10 the crucial role of substrate-induced strain/interface and/or dimensionality effects in stabi-
11 lizing the superconducting phase. To date, the nickelate IL phase is stabilized by optimizing
12 the lattice mismatch between the perovskite and IL phases and the substrate. Specifically,
13 the tetragonal IL phase ($a = 0.392 \text{ nm}, c = 0.328 \text{ nm}$ as measured for the undoped bulk
14 compound [7]) is stabilized onto STO ($a = 0.3905 \text{ nm}$), to minimize the lattice mismatch
15 (approximately -0.4%). However, the STO imposes a large tensile strain on the perovskite
16 precursor phase with a pseudocubic lattice parameter of $a_{pc} = 0.381 \text{ nm}$ (approximately
17 +2.5%). This large tensile strain leads to a larger content of oxygen vacancies if compared
18 to a relatively small compressive strain (approximately -0.5%) when grown onto LaAlO $_3$
19 (LAO) single crystal [8]. In both cases a proper optimization process of the growth condi-
20 tions is necessary to achieve bulk-like transport properties[9].

21 Moreover, stabilizing the Sr-doped NdNiO $_3$ perovskite phase on STO substrate is chal-
22 lenging due to Sr-segregation issues and an unfavorable valence state of the Ni ions[10, 11].
23 These factors necessitate a delicate balance of growth parameters to mitigate epitaxial mis-
24 matches for both the perovskite precursors and IL phases. A novel approach to overcome
25 these challenges involves the development of freestanding nickelate membranes, which are
26 free from substrate-induced strain, using a wet etching method. This method includes grow-
27 ing the material onto a sacrificial layer, which is later removed via selective etching, allowing
28 for the fabrication of oxide membranes while maintaining their structural integrity [12]. Ad-
29 ditionally, utilizing water-soluble sacrificial layers $(\text{Ca, Sr, Ba})_3\text{Al}_2\text{O}_6$, which can be dissolved
30 at room temperature without the use of any chemical pollutants, provides a versatile method
31 to fabricate nickelate membranes [13]. The lattice parameter of these layers can be adjusted

32 from 0.382 nm (100% Ca) to 0.412 nm (100% Ba), thereby enhancing membrane quality and
33 reducing crack formation[14, 15].

34 Here, we report on the fabrication of freestanding perovskite NdNiO_3 membranes using
35 $(\text{Sr,Ca})_3\text{Al}_2\text{O}_6$ sacrificial layers, and on the subsequent topotactic reduction after transfer-
36 ring onto silicon wafers to obtain IL NdNiO_2 membranes with good structural integrity.
37 Very recently, superconducting membranes of infinite-layer nickelates were obtained by per-
38 forming the topotactic reduction prior to transfer, which proves that it is indeed possible
39 to grow the perovskite precursor phases onto specific sacrificial layers, perform topotactic
40 reduction and then achieve a transfer of the superconducting flakes[16, 17]. The reduction
41 of NdNiO_3 membranes proposed in this study aims to gather information about the feasi-
42 bility of stabilizing the IL phase after transferring the membrane, which is then free from
43 any substrate-induced effects. Our experimental approach allows membranes extending up
44 to $5 \times 5 \text{ mm}^2$ to be seamlessly transferred onto various substrates, yielding crack-free flakes
45 of millimeter size. X-ray diffraction measurements have demonstrated that the membranes
46 retain the crystalline quality of the original seed films. Furthermore, we demonstrate the
47 two-fold potential of using a sacrificial layer to stabilize the IL phase via topotactic reduc-
48 tion of nickelate membranes: (1) we could perform the growth of the precursor nickelate
49 onto substrates with an ideal lattice mismatch (*i.e.*, LAO), therefore limiting the formation
50 of extended defects triggered by the strain accommodation highly relevant in the case of
51 STO-grown samples; (2) we could obtain an important information about the substrate's
52 influence on the IL stabilization, making a direct link with bulk preparation of IL nickelates.

53 II. RESULTS AND DISCUSSION

54 An important prerequisite for realizing freestanding crystalline membranes is the choice
55 of the sacrificial layer, which must ensure a good lattice mismatch with both the target mem-
56 brane layers and the substrate, while allowing for perfect etching selectivity. As an example,
57 here, we report on our experience using $\text{La}_{0.825}\text{Sr}_{0.175}\text{MnO}_3$ (LSMO) as a potential sacrifi-
58 cial layer to fabricate NdNiO_3 (NNO3) membranes. Motivated by the fact that LAO single
59 crystals are ideal substrates for the growth of nickelate thin films due to the minimal strain
60 [18], we first optimized NNO3/LSMO//LAO heterostructures. Despite their high structural
61 quality, we were unable to fabricate NNO3 membranes because the LSMO etchant ($\text{HCl}+\text{KI}$ -

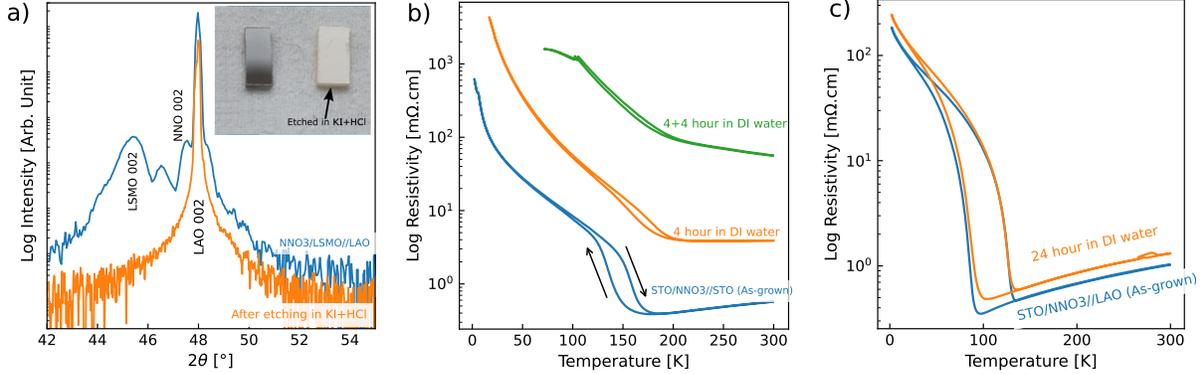


FIG. 1. a) $\theta - 2\theta$ symmetric scan of the 10 nm NNO₃ layer on LSMO on LAO substrate before and after etching in a solution of 4 mg KI, 5 ml HCl (37%) + 200 ml H₂O, with an inset showing a photograph of a 10 nm NNO₃ layer on an STO substrate before and after etching. b-c) Temperature-dependent resistivity of STO-capped NNO₃ grown on STO and LAO substrates, respectively, before and after exposure to DI water.

62 based solution) was not selective, etching NNO₃ similarly to LSMO. Figure 1a shows $\theta - 2\theta$
 63 X-ray diffraction (XRD) patterns for the NNO₃/LSMO//LAO heterostructure before and
 64 after approximately two hours of etching. The XRD pattern, characterized by Laue os-
 65 cillations around the LAO (001) peaks due to the perfect NNO₃-LAO lattice mismatch,
 66 completely disappears after etching. This confirms the non-selectivity of the HCl+KI-based
 67 solution, which was also tested with a bare NNO₃//STO sample. The photograph in the
 68 inset of Figure 1a shows NNO₃//STO before and after etching, in which the NNO₃ layer is
 69 completely removed. Similar results were obtained (not shown) even when the NNO₃ layers
 70 were encapsulated between two 10 nm thick STO layers as a potential protection from direct
 72 contact with the LSMO etching solution.

73 To cope with this problem, we resorted to water-soluble sacrificial buffer layers already
 74 used in the literature to fabricate perovskite membranes [13]. These are particularly promis-
 75 ing for the fabrication of nickelate membranes due to their good structural compatibility with
 76 nickelates. For example, Ca₃Al₂O₆ (CAO) has a cubic unit cell (space group Pa $\bar{3}$) with a
 77 lattice parameter of 1.526 nm, which closely matches the pseudocubic unit cells of both LAO
 78 and NNO₃ ($a_{\text{CAO}} = 1.526 \sim 0.381 \times 4$ nm). Moreover, substituting Ca with Sr in specific
 79 ratios allows for tuning the CAO lattice parameter from $a/4 \sim 0.381$ nm for Ca₃Al₂O₆ to $a/4$
 80 ~ 0.396 nm for Sr₃Al₂O₆ (SAO), which dissolves in deionized (DI) water much faster (in a

81 few minutes compared to approximately two days for CAO) due to the predominantly ionic
82 Sr–O bonds [15]. This extended dissolution time necessitates studying the effect of DI-water
83 on the functional properties of NNO3, as protonation effects have been shown to play a
84 role on the related transport properties [19]. Figure 1b shows the temperature-dependence
85 resistivity measurements for STO-capped NNO3 thin films before and after immersion in
86 DI-water of various duration. It is seen that properly optimized NNO3 thin films grown onto
87 STO are very sensitive to DI-water, and the usual hysteretic metal-to-insulator transition
88 (MIT) with an onset temperature of approximately 140 K is significantly altered until the
89 sample becomes fully insulating after eight hours of immersion. This behavior is absent
90 when NNO3 is grown onto LAO substrates, where similar transport properties are observed
91 even after one day in DI-water, as shown in Figures 1c. This compelling difference is most
92 likely originating from the different strain state that the NNO3 thin films experience when
93 grown onto STO (tensile) and LAO (slightly compressive) substrates which is found to affect
94 the intrinsic content of oxygen vacancies [8]. To counteract the effect of DI-water on the
95 fabricated membranes, we performed an oxygen post-annealing process as will be introduced
96 later.

97 **Epitaxial growth of the heterostructures**

98 We used a pulsed laser deposition technique to grow NNO3-based heterostructures (HTs)
99 using several sacrificial layers, such as $\text{Sr}_3\text{Al}_2\text{O}_6$ (SAO), $\text{Ca}_3\text{Al}_2\text{O}_6$ (CAO), and $\text{Ca}_2\text{Sr}_1\text{Al}_2\text{O}_6$
100 (CSAO) on both STO and LAO substrates (please refer to the Experimental Section for de-
101 tails). The NNO3 films directly grown onto the sacrificial layers appeared to exhibit modified
102 transport properties, and the sacrificial layers became insoluble in water, suggesting that
103 interdiffusion modifies the electronic and chemical properties of both layers. **In addition, the**
104 **use of LAO layers as a barrier to prevent interdiffusion (i.e., LAO/NNO3/LAO/CAO//LAO)**
105 **resulted in interdiffusion between the LAO and CAO layers. Therefore, the 10 nm thick**
106 **NNO3 films were encapsulated between two layers of STO, approximately 10–25 unit cells**
107 **thick, which prevented potential interdiffusion of ions between the sacrificial layers and**
108 **NNO3[20].** Reflection high-energy electron diffraction (RHEED) patterns taken after the
109 growth of sacrificial, STO bottom, and NNO3 layers showed 2D streaky features, indicating
110 clear layer-by-layer growth and an atomically flat surface, as illustrated in Figures 2a–b

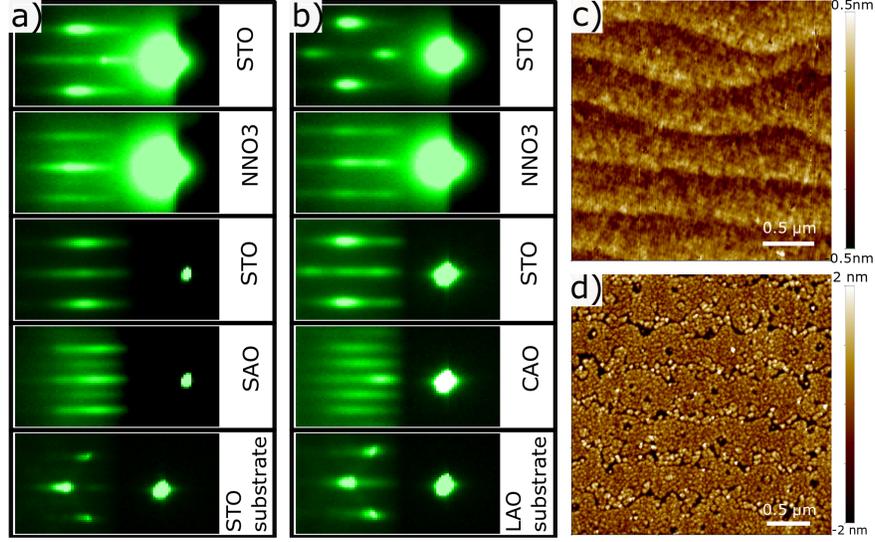


FIG. 2. a–b) RHEED diffraction patterns for SAO-STO and CAO-LAO HTs along the (001) direction of the substrates upon the completion of each layer’s growth. The order of the RHEED images is from bottom to top, following the structure of the samples at each corresponding stage. c–d) AFM topography images for SAO-STO and CAO-LAO HTs acquired after the growth, respectively.

111 for the STO/NNO3/STO/SAO//STO and STO/NNO3/STO/CAO//LAO HTs, hereafter
 112 referred to as SAO-STO and CAO-LAO, respectively. Results obtained using the CSAO
 113 sacrificial layer are shown in Figures S1a–b. After the growth of the top STO layer, the
 114 RHEED pattern exhibited a mix of 2D streaks and 3D transmission spots, indicating that
 115 the surface had developed a partial 3D morphology. This was also confirmed by Atomic
 116 Force Microscopy (AFM) measurements, with root-mean-square (rms) surface roughness
 118 ranging from 0.2 nm to 0.7 nm, as shown in Figures 2c–d.

119 Figures 3a–b show the θ – 2θ XRD symmetric scans of both the CAO-LAO and SAO-
 120 STO HTs. The clear diffraction peaks of the sacrificial layers and the STO/NNO3/STO
 121 HTs confirm that all layers are grown with good crystalline quality. The STO multipeak
 122 structure for the CAO-LAO HTs might be associated with a partial strain gradient, which
 123 was also observed for STO/NNO3/STO/CSAO//LAO (CSAO-LAO) HTs (see Figure S2a).
 124 Reciprocal space mapping presented in Figures 3c–d, acquired around the asymmetric 103
 125 diffraction peak of the substrates, show that the SAO sacrificial layer is not fully in-plane
 126 strained to the STO; surprisingly, the subsequent layer of NNO3 exhibits the same in-plane

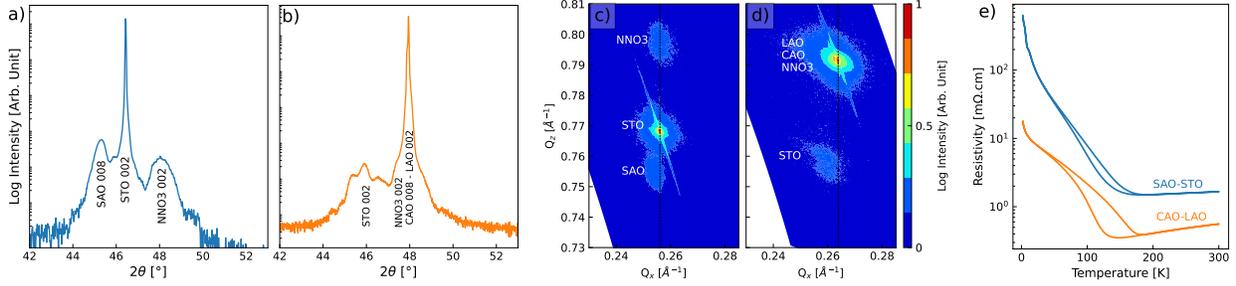


FIG. 3. Structural characterization of the as-grown heterostructures. $\theta - 2\theta$ symmetric scans of the as-grown a) SAO-STO and b) CAO-LAO heterostructures. Reciprocal space maps around the STO and LAO 103 asymmetric diffraction peaks for the c) SAO-STO and d) CAO-LAO heterostructures. e) Temperature-dependent resistivity of both SAO-STO and CAO-LAO heterostructures.

127 lattice parameter as the STO substrate. For the CAO-LAO HTs, both the sacrificial layer
 128 and NNO3 are fully strained to the LAO, as expected from the good lattice mismatches,
 129 while the STO is partially relaxed. To attest to the quality of the NNO3 films, we also
 130 performed temperature-dependent resistivity, and as reported in Figure 3e, both HTs exhibit
 131 the characteristic features of perovskite nickelate thin films with metallic behavior at high
 132 temperatures followed by a hysteretic metal-to-insulator transition below approximately
 133 150 K, with a resistance change of at least two orders of magnitude [21]. In particular, the
 134 CAO-LAO HT shows better metallic behavior, with an overall resistivity at 300 K lower than
 135 $1 \text{ m}\Omega\cdot\text{cm}$, and a larger hysteresis, likely resulting from the better lattice match with the LAO
 136 single crystal and the reduced internal strain state of the HTs, which leads to fewer extended
 138 defects and/or oxygen vacancies. On the other hand, the smaller hysteresis in SAO-STO HT,
 139 accompanied also by a modified curvature of the temperature-dependent resistivity curve,
 140 suggests that the large tensile strain imposed by the STO substrate, along with growth on
 141 the SAO sacrificial layer, may locally affect the electronic properties of NNO3[9], leading
 142 to lower quality membranes. Indeed, from the XRD of the NNO3 002 diffraction peak, we
 143 measured values around 48° , which is lower than the 48.5° usually measured for direct growth
 144 onto the STO substrates[10]. Overall, these results indicate that the sacrificial layers with
 145 the adjacently grown STO thin films do not affect the quality of the NNO3 thin films, which
 146 exhibit good epitaxial growth. It is worth mentioning that similar transport properties for
 147 NNO3 are measured for CSAO-LAO HTs, while STO/NNO3/STO/SAO//LAO (SAO-LAO)
 148 HTs resulted in a completely insulating behavior of the NNO3, even though the RHEED

149 patterns indicated 2D-like growth of the layers (see Figure S2c).

150 Epitaxial lift-off (membrane release)

151 Figure 4a–c schematically shows the process flow for fabricating freestanding membranes.
152 First, water-soluble sacrificial layers are grown onto STO and/or LAO single crystals, fol-
153 lowed by the growth of the STO/NNO3/STO heterostructure. A polymer support (PDMS),
154 attached to a glass slide, is cut into pieces larger than the sample surface, and brought into
155 conformal contact with the sample surface. Then, the stack of polymer and sample is im-
156 mersed in DI-water to selectively etch the sacrificial layer. The etching time for the sacrificial
158 layers varies from one to two hours for SAO, up to two days for CSAO and CAO. After ver-
159 ifying the complete etching of the sacrificial layer, the glass+PDMS+heterostructure stack
160 is released from the substrate, then placed in contact with the recipient substrate (SiO_2/Si)
161 using a transfer system with micrometer XYZ stages. The SiO_2/Si substrate had been
162 previously ultrasonically cleaned in acetone and isopropyl alcohol. After annealing the en-
163 tire stack in air at 70°C for 10 minutes to promote adhesion on the SiO_2/Si substrate, the

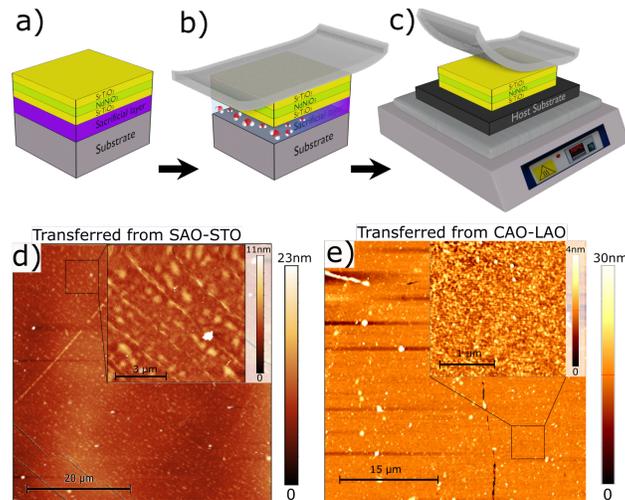


FIG. 4. a–c) Freestanding membranes fabrication process flow. a) Epitaxial growth of the sacrificial (water-soluble) layer and the STO/NNO3/STO heterostructure. b) Fixing the polymer support on sample surface and etching in de-ionized water. c) Transfer to the host substrate and peel-off of the polymer support. d-e) AFM topography images of the heterostructure transferred from SAO-STO and CAO-LAO respectively.

164 PDMS stamp is then carefully peeled off by raising the glass+PDMS support using one of
 165 the micrometer stages of our system.

166 Depending on the lattice parameters of the sacrificial layer and substrate, the resultant
 167 membranes exhibited different characteristics. The membranes obtained by dissolving SAO
 168 and CAO sacrificial layers were characterized by a complete transfer onto the polymer sup-
 169 port, yet with notably different numbers and sizes of cracks. Membranes released from
 170 SAO-STO exhibited parallel micrometer-scale cracks in one direction, which were only vis-
 171 ible by AFM, while the CAO-LAO membranes displayed fewer cracks having no particular
 172 direction, as shown in Figure 4d-e. Such differences in crack formation between these two
 173 types of membranes can be attributed to the strain state and number of defects; a low lattice
 174 mismatch between NNO3, CAO, and the LAO substrate permits coherent epitaxial growth
 175 of the films, which was confirmed by RSM measurements (see Figure 3c-d). On the other
 176 hand, membranes released from CSAO-LAO tended to bend upon themselves and curled
 177 into microscopic rolls, as shown in the SEM image of Figure S3c.

178 To further study the structural integrity of the freestanding membranes, we conducted
 179 XRD $\theta - 2\theta$ symmetric and asymmetric scans of the membranes transferred onto SiO₂(300
 180 nm)/Si wafers. After transfer, the membranes were annealed for 3 hours at 300°C under an
 181 oxygen flow to mitigate possible protonation effects. In Figure 5a, we present the $\theta - 2\theta$

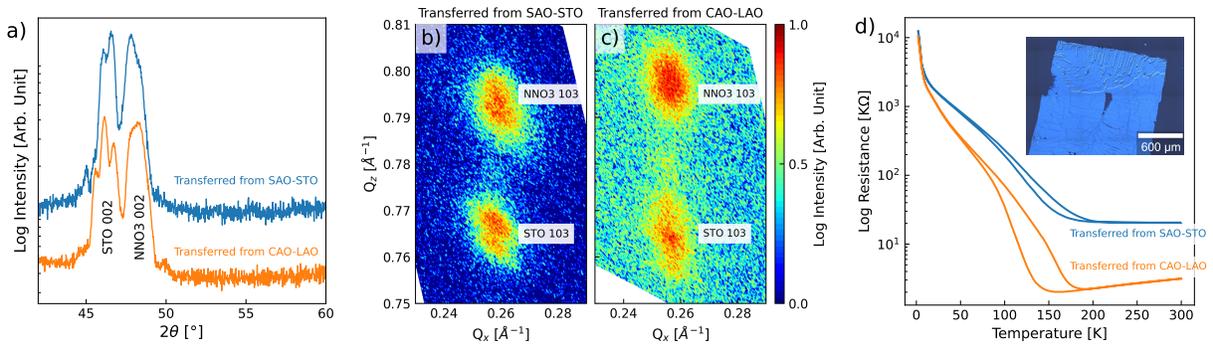


FIG. 5. a) $\theta - 2\theta$ scan and b–c) Reciprocal space maps around NNO3 and STO 103 diffraction peaks of the STO/NNO3/STO heterostructures transferred from SAO-STO and CAO-LAO, respectively. d) Temperature-dependent resistance of STO/NNO3/STO heterostructures membranes after transferring on to SiO₂/Si wafer and annealing for 3 hours at 300°C under oxygen flow. Inset: optical image of the freestanding membrane on SiO₂/Si substrate with micro Au-electrodes and Al wire bonds.

182 symmetric scan of STO/NNO3/STO heterostructure membranes transferred from SAO-STO
183 and CAO-LAO HTs. It is seen that all membranes exhibit (002) diffraction peaks for STO
184 and NNO3, similar to those of the as-grown HTs before release, confirming the conservation
185 of crystalline integrity for both NNO3 and STO layers. The three side-by-side peaks observed
186 in the STO layers, which have also been measured in other studies [16, 17], result from
187 the Laue oscillations of the bottom and upper STO layers (Figure S4b), as confirmed by
188 XRD simulations performed using a kinematic simulation MATLAB program[22]. The RSM
189 measurements performed on the membranes showed that, after release, the three layers of
190 the STO/NNO3/STO HTs remain epitaxially coupled, resulting in an equilibrium strain
191 state, as shown in Figure 5b-c. The final strain of the layers in the membranes results from
192 a trade-off between their elastic properties, thickness, and the initial strain withstanding
193 during growth of the stack and assured by the choice of the substrate[23]. As a result of
194 this process, in all membranes, the NNO3 layer is strained to the STO buffer layers, and
195 conversely the STO layer is finely strained to NNO3. The higher applied strain by the STO
196 layers, compared to NNO3, is likely due to their respective thicknesses, as the two STO
197 layers are double the thickness of NNO3. Consequently, the NNO3 thin film grown onto
198 LAO do not show the expected bulk values, but during release the in-plane lattice parameter
199 is partially adjusted to the STO one. The lattice parameters and the calculated in-plane and
200 out-of-plane strains in the membranes extracted from the RSM data are listed in Table I (see
201 also Table S1).

202 In Figure 5d, we present the temperature-dependent resistance of the membranes, which
203 were measured after the deposition of gold electrodes and aluminum wire bonding (see inset).
204 The membranes preserved their transport properties that were shown in Figure 3e, with both
205 the high-temperature metallic behavior and the low-temperature insulating phase, featuring
206 a well-defined metal-to-insulator transition of the NNO3 layer and similar hysteresis as
207 already reported for the grown HTs. **Note that the difference in the magnitude of resistivity**
208 **shown in Figure 3e and resistance shown in Figure 5d stems from the method by which**
209 **the transport is measured. However, both display temperature-dependent resistance of the**
210 **same order of magnitude when measured in a two-point contact configuration, as shown**
211 **in Figure S8.** These results are highly reproducible, as can be seen in the Figure S4a in
213 supporting information.

TABLE I. Lattice parameters and strain states of the STO/NNO3/STO freestanding membrane heterostructures transferred from SAO-STO to CAO-LAO. Note: The strain state in the membranes depends on the thickness of the STO buffer layers; here, the STO thickness is ~ 10 nm.

Material	a-axis [\AA] ± 0.01	c-axis [\AA] ± 0.01	ip strain [%]	oop stain[%]
STO of SAO-STO	3.87	3.91	-0.9	0.13
NNO of SAO-STO	3.87	3.78	1.63	-0.74
STO of CAO-LAO	3.89	3.92	-0.38	0.51
NNO of CAO-LAO	3.89	3.76	2.15	-1.26

214 Topotactic reduction of the membranes

215 After the successful fabrication of the STO/NNO3/STO membranes, we performed a
 216 topochemical reduction by placing them in an evacuated silica tube sealed with a membrane-
 217 valve, where 0.5 g of CaH_2 powder was put in direct contact with them, as used in prior
 218 studies[10]. The process was optimised by a systematic series of steps, with $\theta - 2\theta$ scans
 219 and temperature-dependent resistance measurements performed ex situ after each step to
 220 assess the degree of topotactic reduction. A temperature of 240°C was found to be optimal
 221 for reduction, high enough to enable the reduction and low enough to avoid any damage
 222 to the membranes. In Figure 6, we present $\theta - 2\theta$ symmetric scans and temperature-
 223 dependent resistance measurements of two steps of the topotactic reduction process. After
 224 a first step of reduction, the NNO3(002) XRD diffraction peak considerably decreased in
 225 intensity for membranes obtained from SAO-STO HTs, while for CAO-LAO membranes,
 226 the XRD peak, still intense, began to shift towards higher 2θ values as expected for a proper
 227 stabilization of the IL phase. An additional step of reduction resulted in a complete shift
 228 to the typical 2θ value expected for IL films, for the membranes obtained from CAO-LAO
 229 HTs, with substantial intensity (Figure 6b). Notably, the $\theta - 2\theta$ symmetric scans, give the
 230 relevant information that the stabilization of the IL phase is obtained only in the case of
 231 membranes released from the CAO-LAO HTs while the ones obtained from the SAO-STO
 232 HTs practically decomposed, as demonstrated by the almost complete absence of the IL
 233 diffraction peak in Figure 6a. This disparity could be ascribed to intrinsic defects present
 234 in the related perovskite precursor phase, most likely linked to the large tensile strain that

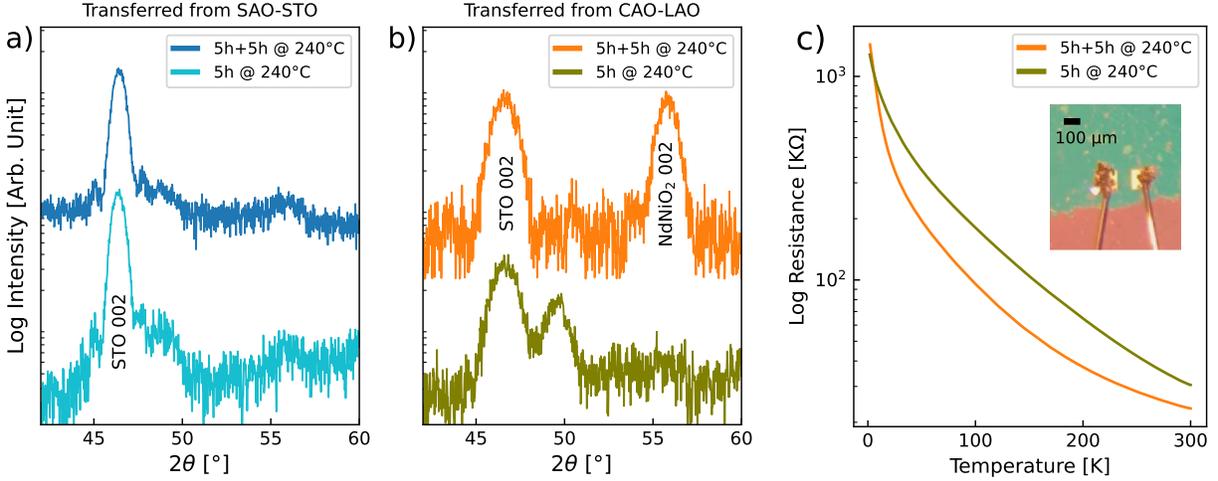


FIG. 6. a–b) $\theta - 2\theta$ symmetric scans of the STO/NNO₃/STO heterostructure membranes after topochemical reduction for 5 hours at 240°C, followed by an additional 5 hours of reduction at the same temperature, for membranes transferred from a) SAO-STO and b) CAO-LAO. c) Temperature-dependent resistance of the freestanding infinite-layer membranes transferred from CAO-LAO; inset: optical microscope image of a reduced membrane after bonding.

236 NNO₃ experiences during growth onto STO and the adjacent sacrificial layer. In particular,
 237 as already highlighted above, the membranes released from CAO-LAO HTs showed better
 238 metallic behavior and a larger hysteresis (Figure 5d), while from the Table I, we can note
 239 that only for CAO-LAO membranes the STO lattice parameter is closer to the bulk one,
 240 therefore exerting a lower compressive strain on the forming IL tetragonal crystal structure,
 241 if compared to the one obtained in the case of SAO-STO membranes.

242 Transmission electron microscopy observations of cross sections of the membranes trans-
 243 ferred from CAO-LAO confirm their high crystalline quality as shown in Figure 7, although
 244 regions with Ruddlesden-Popper-type defects can be easily be recognized as already shown
 245 in literature for thin films and membranes Ref[17]. Their topotactic reduction is confirmed
 247 by both the observation of a reduced out-of-plane cell parameter, as seen in high-angular an-
 248 nular dark field (HAADF) images (Figure 7a), and the confirmation that the apical oxygen
 249 atoms have been removed, leaving the infinite-layer with oxygen only in the Ni-O planes, as
 250 deduced from integrated Differential Phase Contrast (iDPC) observations (Figure 7b).

251 Although both XRD patterns and TEM observations indicate the formation of a high
 252 crystalline quality for the IL phase obtained from CAO-LAO membranes, they showed insu-

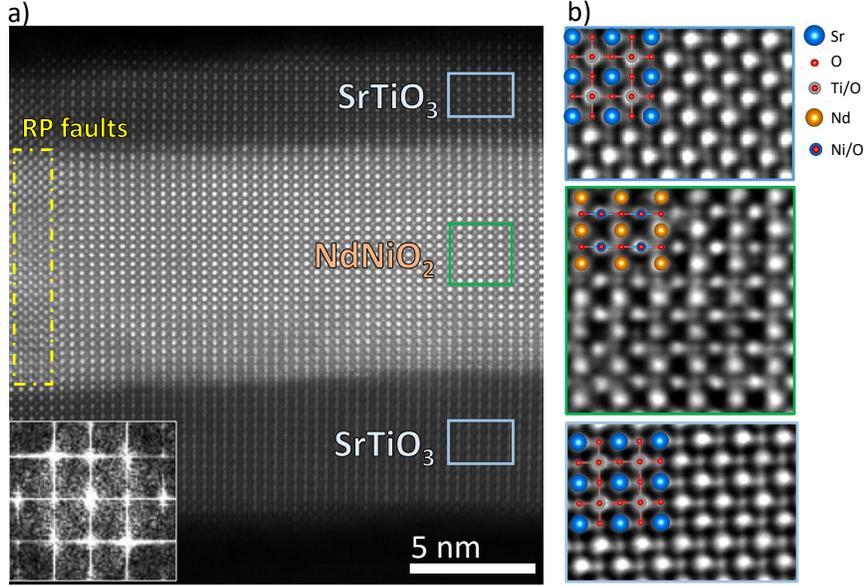


FIG. 7. a) The high-angle annular dark field (HAADF) STEM image obtained from the infinite-layer NdNiO_2 free-standing membrane transferred from CAO-LAO. The yellow dashed square outlines a region with a Ruddlesden-Popper fault. The fast-Fourier transform pattern obtained from the infinite-layer nickelate membrane is shown in the inset. The out-of-plane parameter is significantly lower than the in-plane one, thus confirming the infinite-layer nature of the membrane. b) Integrated Differential Phase Contrast (iDPC) image obtained from the central region of the membrane. The oxygen atoms are now seen along with the heavier species. The oxygen atoms are only seen in the Ni-O planes and not in the Nd-O planes, which again confirms the infinite-layer structure.

253 lating transport properties. This insulating behavior cannot be attributed to further cracks
 254 formation during the topotactic reduction process, since no additional crack formation was
 255 observed by optical microscopy and AFM as shown in Figure S6. On the other hand, from
 256 a structural point of view, we observed a decrease in the c-axis lattice parameter of the
 257 STO buffer layers after reduction, changing from 0.3920 nm to 0.3896 nm. This change indi-
 258 rectly indicates an increase in the in-plane lattice parameter of the STO layer, which thereby
 259 adapts itself to the a-axis of the forming IL-phase. Furthermore, the c-axis lattice parameter
 260 of STO buffer layers is observed to be modified compared to what is measured for the STO
 261 substrate, as shown in Figure S5. Finally, the fully insulating behavior of IL membranes,
 262 which is similar to what has been measured for bulk IL [6], points to the experimental fact

263 that a greater strain effect from the STO buffer layer (a substrate-like), is necessary to
264 enable a more coherent stabilization of the IL phase with the expected transport properties.

265 To understand the feasibility of reducing the STO/NNO3/STO heterostructure in the
266 presence of a sacrificial layer and LAO substrate, we performed topotactic reduction on a
267 sample prior to transfer. Figure S7 shows θ - 2θ symmetric scans and temperature-dependent
268 resistivity of a CAO-LAO heterostructure before and after a two-step topochemical reduc-
269 tion. After the first reduction (5 hours at 240°C), a very small and broad peak appeared
270 at the expected 2θ value for IL, which rather than transformation to IL may indicate a
271 transformation towards intermediate and/or spurious phases accompanied also by an insu-
272 lating temperature-dependent resistivity. Further reduction (2 hours at 240°C), resulted in
273 no XRD peak at all with a further increase of the overall resistance, as indeed expected due
274 to the large difference of the in-plane lattice parameters between LAO (3.79 Å) and IL-phase
275 (3.92 Å).

276 CONCLUSION

277 We reported about the successful growth onto different substrates of epitaxial STO-
278 encapsulated NdNiO₃ (NNO3) heterostructures with water-soluble (Ca,Sr)₃Al₂O₆ sacrificial
279 layers. The as-grown HTs as well as the released membranes showed similar structural and
280 transport properties, although, the overall strain relaxation during membrane formation
281 rendered different lattice-parameters as shown in Table I. We demonstrated by TEM and
282 XRD measurements that an infinite-layer phase could be properly stabilized from CAO-LAO
283 HTs released membranes. The latter, nevertheless, displayed a fully insulating behaviour
284 similarly to bulk. From our structural study it appeared clear that the STO buffer layers re-
285 adjust their lattice parameters to the IL-phase one (*i.e.* $a = 0.392$ nm) during the topotactic
286 reduction. Thus, not providing the optimal (compressive) strain to the IL-phase, which
287 might be the necessary and sufficient condition to grant the ideal transport properties as
288 observed in the case of IL nickelate thin films. Finally, our results highlight the key role
289 played by the substrate-induced epitaxial strain on the formation of the nickelates IL phase.
290 We are confident that the optimization of the sandwich material, either in its nature or
291 thickness, will allow fine-tuning of the different strains and lead to freestanding nickelates
292 IL membrane with expected transport and electronic properties.

293 III. EXPERIMENTAL

294 *a. Epitaxial film fabrication:* The epitaxial growth of NNO3-based HTs onto STO
295 and LAO substrates was done by pulsed laser deposition using a 248 nm KrF excimer laser,
296 utilizing single-crystal targets from Toshiba Manufacturing CO LTD. The STO substrates
297 were prepared by etching in an NH_4F -buffered HF solution, then annealed for 2 hours at
298 950°C in air to obtain a well-defined TiO_2 -terminated step-terraced surface. In contrast,
299 the LAO substrates were annealed for 10 hours at 1000°C to achieve an AlO_2 -terminated
300 step-terraced surface. Prior to growth, each substrate was pre-annealed for 1 hour at 800°C
301 under a pressure of 0.3 mbar in an oxygen flow to ensure a sharp step-and-terrace surface.
302 Approximately 20 nm $\text{Sr}_3\text{Al}_2\text{O}_6$ (SAO), $\text{Ca}_3\text{Al}_2\text{O}_6$ (CAO), and $\text{Ca}_2\text{Sr}_1\text{Al}_2\text{O}_6$ (CSAO) sacrifi-
303 cial layers were grown on top of the STO(LAO) (001) substrates at a substrate temperature
304 of 800°C and an oxygen partial pressure of $P_{\text{O}_2} = 1.2 \times 10^{-5}$ mbar, using a laser fluence of
305 1.2 J/cm^2 and a $1 \times 1.4 \text{ mm}^2$ laser spot size on the targets. The bottom STO buffer layers
306 (6-10 nm) were grown on the sacrificial layers under the same growth conditions. Next, the
307 10 nm NNO3 layers were grown on top of the STO buffer layers at a temperature of 675°C
308 and $P_{\text{O}_2} = 0.3$ mbar, with a laser fluence of 3.3 J/cm^2 and a $1 \times 1.4 \text{ mm}^2$ laser spot size.
309 Finally, the top STO layer was grown at a T of 575°C and $P_{\text{O}_2} = 0.3$ mbar, with a laser
310 fluence of 1.2 J/cm^2 and a $1 \times 1.4 \text{ mm}^2$ laser spot size.

311 *b. Transfer of freestanding membranes:* A flexible polymer (PDMS) was ad-
312 hered to the heterostructure surface (Figure 4b), and then the assembly was immersed in
313 room-temperature de-ionized water to dissolve the sacrificial layers. After dissolution, the
314 freestanding membranes were transferred to SiO_2/Si substrates by placing and pressing the
315 membrane with PDMS onto the heated (70°C) silicon wafer (Figure 4c). By peeling off the
316 PDMS support, the membranes remain on the wafers and detach from the support.

317 *c. Characterization:* The surface morphology of the samples was acquired using a
318 Park XE7 (Park System) atomic force microscope (AFM) in true non-contact mode. The
319 XRD data were collected using Bruker D8 Advance and PANalytical X'Pert Pro diffractome-
320 ters with a $\text{Cu-K}\alpha$ radiation source (0.1154056 nm). The transport properties of the het-
321 erostructures on the single-crystal substrates were studied using a Dynacool system (Quan-
322 tum Design) and measured using the van der Pauw method on $5 \times 5 \text{ mm}^2$ samples by applying
323 current amplitudes of $10 \mu\text{A}$. To measure the transport of the transferred membrane flakes,

324 Au electrodes were first fabricated by photolithography; then, the electrodes were bonded,
325 and the transport measurements were conducted in two-point contact mode. The high-angle
326 annular dark-field (HAADF) images were acquired in a double-corrected Thermofisher Spec-
327 tra 300 (S)TEM microscope operated at 300 KV, using a convergence semi-angle of around
328 20 mrad. The oxygen sublattice was imaged by means of integrated differential phase con-
329 trast (iDPC) imaging using the segmented Panther detector from Thermofisher and a camera
330 length of around 145 mm. For the STEM experiments, a cross sectional view lamella was
331 prepared using a focused ion beam (FIB) Helios 5 UX from Thermofisher.

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Supporting information: Freestanding perovskite and infinite-layer nickelate membranes

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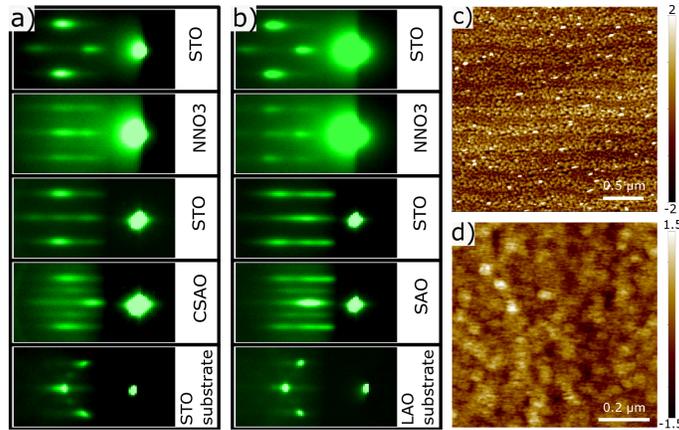


FIG. S1. a–b) RHEED diffraction patterns for CSAO-LAO and SAO-LAO heterostructures along the (001) direction of the substrates upon the completion of each layer’s growth. c–d) AFM topography images of CSAO-LAO and SAO-LAO HTs acquired after the growth, respectively.

TABLE S1. Lattice parameters and strain states of a STO(3nm)/NNO3(10nm)/STO(3nm) free-standing membrane transferred from CAO-LAO.

Material	a-axis [\AA] ± 0.01	c-axis [\AA] ± 0.01	ip strain [%]	oop stain[%]
NNO of CAO-LAO	3.83	3.79	0.6	-0.48

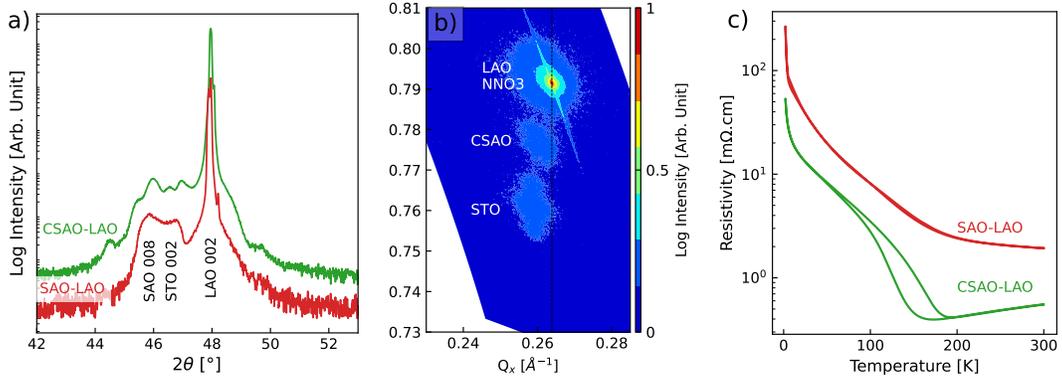


FIG. S2. a) $\theta - 2\theta$ scans of the as-grown CSAO-LAO and SAO-LAO heterostructures. b) Reciprocal space map around the LAO 103 asymmetric diffraction peak for the CSAO-LAO heterostructure. c) Transport measurements of the as-grown CSAO-LAO and SAO-LAO heterostructures.

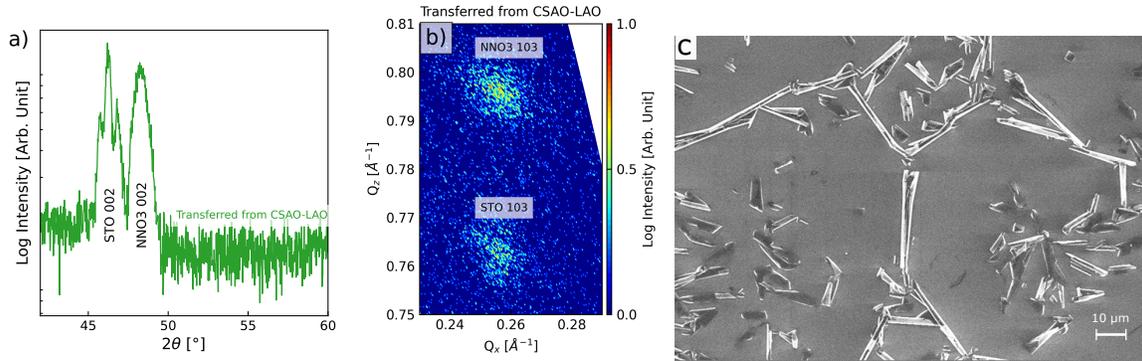


FIG. S3. a) $\theta - 2\theta$ symmetric scan, b) Reciprocal space map around NNO3 and STO 103 diffraction peak, and c) SEM image of the STO/NNO3/STO heterostructure transferred from CSAO-LAO.

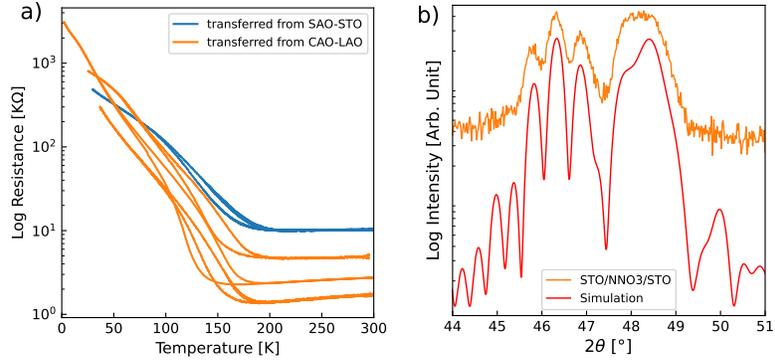


FIG. S4. a) Temperature-dependent resistance measurements of as-grown CAO-LAO and SAO-STO heterostructures for multiple membrane samples, b) $\theta - 2\theta$ symmetric scans of STO/NN03/STO heterostructure transferred from CAO-LAO and corresponding simulation using lattice parameters from Table 1.

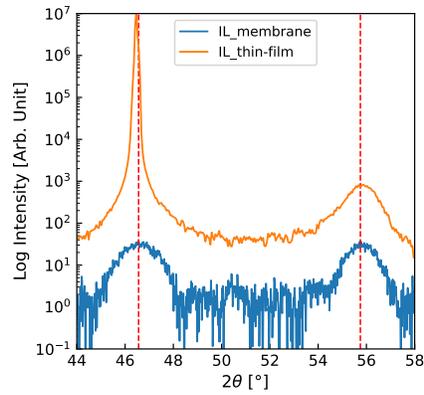


FIG. S5. $\theta - 2\theta$ symmetric scans of infinite-layer stabilized in the form of a thin film (in orange) and stabilized in the form of a membrane (in blue).

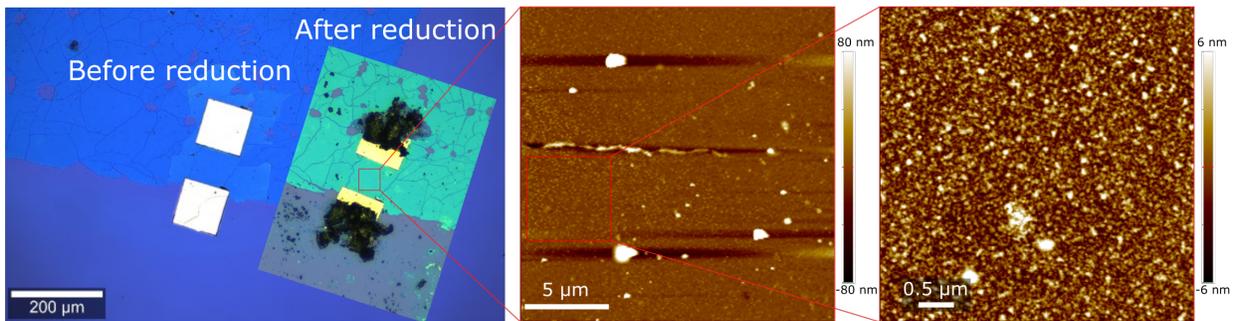


FIG. S6. Optical and AFM topography image of CAO-LAO membranes before and after topotactic reduction

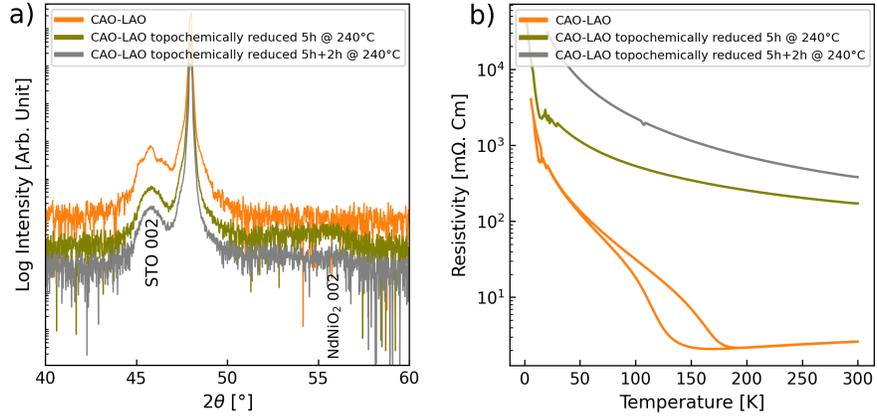


FIG. S7. a) $\theta - 2\theta$ symmetric scans and b) Temperature-dependent resistivity of a CAO-LAO heterostructure, before and after topochemical reduction for 5 hours at 240°C, followed by an additional 2 hours of reduction at the same temperature.

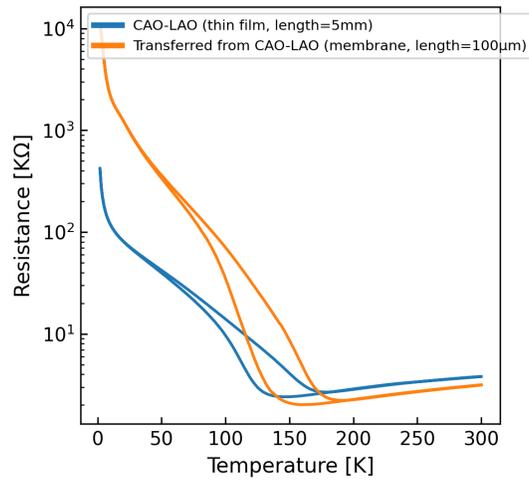


FIG. S8. Temperature-dependent resistance of a CAO-LAO heterostructure in thin film and membrane form, measured in two-point contact configuration.

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